



New Advances, Methods, and Applications for Micro Inertial Sensors, 2nd Edition

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Message from the Guest Editors

MEMS technology opens up a new avenue for manufacturing low-cost and small-volume inertial measurement units. Micro inertial sensors are ubiquitous, and can be found in smartphones, cars, and smartwatches. Signals for the micro inertial sensors are sampled and processed for various applications, e.g., health monitoring, vibration sensing, position, and navigation. For position and navigation applications in particular, micro inertial sensors are utilized for measuring the position, velocity, and attitude information, i.e., the accelerometer is utilized to detect the pedestrian step and update the position; the micro inertial sensors are employed in a car to integrate with the GNSS to provide more reliable positional information; the UAV measures its attitude using the measurements from the micro inertial sensor. Minimizing the micro inertial sensor volume and improving the quality of its measurements have attracted much attention in the scientific community. New principles, advanced manufacturing technology, and novel signal processing algorithms are expected to improve its performance and extend its applications.





Editor-in-Chief

Message from the Editor-in-Chief

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